

DAMPER FOR A GAUGE SENSOR IN A DRY ETCH CHAMBER

Abstract of the Disclosure

A damper for protecting a gauge sensor measuring the pressure of a dry etch chamber. The damper includes a vacuum tube for connecting the gauge with the chamber and at least one plate for blocking the plasma of the chamber from directly striking against the sensor. The at least one plate is disposed at the inner wall of the vacuum tube to effectively prevent the plasma from attaching onto the sensor so as to maintain the sensitivity of the sensor and prolong the lifetime of the gauge.